



IPW

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:

Confirmation No.: 7514

Takaei SASAKI et al

Group Art Unit: 1746

Serial No.: 10/712,032

Examiner: Michail Kornakov

Filed: November 14, 2003

Attorney Docket No.: 101136-00101

For: METHOD AND APPARATUS FOR DRY-ETCHING HALF-TONE PHASE-SHIFT FILMS, HALF-TONE PHASE-SHIFT PHOTOMASKS AND METHOD FOR THE PREPARATION THEREOF, AND SEMICONDUCTOR CIRCUITS AND METHOD FOR THE FABRICATION THEREOF

AMENDMENT UNDER 37 CFR § 1.111

Mail Stop: AF

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

Date: June 3, 2005

Sir:

In reply to the outstanding Office Action dated March 3, 2005, please amend the above-identified patent application as follows: